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Substitute for form 1449/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

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Complete if Known

Application Number	10/773,796
Filing Date	02/06/2004
First Named Inventor	Veerasamy, Vijayen
Art Unit	1792
Examiner Name	Marianne Padgett
Attorney Docket Number	07-09-4750

Sheet 2 of 4

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		Yamamoto, Takayuki, "Tribology of protective carbon films for thin film magnetic disk," Journal of the Surface Finishing Society of Japan, Vol. 44 (No. 10): 790-794, 1993.	
		Bhushan, Bharat, et al., "Microscale mechanical and tribological characterization of hard amorphous carbon...", Surface and Coatings Technology, Vol. 76-77:655-669, 1995.	
		Bhushan, Bharat, et al., "Micro-scale tribological characterization...", International Conference on Metallurgical Coatings and Thin Films, G3.05, at 232, April 24-28, 1995.	
		NSIC/ARPA Ultra-High Density Recording (UHDR) Project, Magnetic Disk Component Technical Progress Report, Quarter Ending December 31, 1994.	
		Cutiongco, Eric C., et al., "Tribological behavior of amorphous carbon nitride...", ASME/STLE Tribology Conference; republished in Journal of Tribology, vol. 118:543-548, 1996	
		Khurshudov, Andrei, et al., "Microtribological characterization of carbon nitride coatings," Proceedings Int'l Tribology Conference, Yokohama, 1995.	
		Koidl, P., et al., "Plasma Deposition, Properties and Structure of Amorphous Hydrogenated Carbon Films," Materials Science Forum, Vols. 52-53, pp. 41-70, 1989.	
		McKenzie, D.R., et al., "Compressive-Stress-Induced Formation of Thin-Film Tetrahedral Amorphous Carbon," Physical Review Letters, Vol. 67(6):773-76, 1991.	
		Cuomo, Jerome J., et al., "Vapor deposition processes for amorphous carbon films with sp ³ fractions approaching diamond," J. Appl. Phys. Vol. 70(3):1706-1711, 1991.	
		Schwan, J.S., et al., "Tetrahedral amorphous carbon films prepared by magnetron sputtering and dc ion plating," J. Appl. Phys. Vol. 79(30):1416-1422, 1996.	

Examiner Signature	Date Considered
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		Lossy, Richard, et al., "Properties of amorphous diamond films prepared by a filtered cathodic arc," Journal of Applied Physics, Vol. 77(9):4750-4756, 1995.	
		Lossy, Richard, et al., "Filtered arc deposition of amorphous diamond," Appl. Phys. Lett. 61(2):171-173, 1992.	
		Anders, Simone, et al., "Macroparticle-free thin films produced by an efficient vacuum arc deposition technique," J. Appl. Phys. 74(6):4239-4241, 4239, 1993.	
		Sanders, David M., et al., "Coating Technology Based on the Vacuum Arc-A Review," IEEE Transactions on Plasma Science, Vol. 18(6):883-893, 1990.	
		Lifshitz, Y., et al., "Growth mechanisms of DLC films from C+ ions: experimental studies," Diamond and Related Materials, Vol. 4:318-323, 1995.	
		Ager, Joel W., III, "Optical Characterization of Sputtered Carbon Films," IEEE Transactions on Magnetism, Vol. 29(1):259-263, 1993.	
		Bhushan, Bharat, et al., "Handbook of Tribology: Materials, Coatings, and Surface Treatments", 1991.	
		Franceschini, D.F., et al., "Internal stress reduction by nitrogen incorporation in hard amorphous carbon thin films," Appl. Phys. Lett. 60(26):3229-3231.	
		Jiang, Z., et al., "Nanotribological Evaluations of Hydrogenated Carbon Films as Thin as 5 nm on Magnetic Rigid Disks" IEEE Transactions on Magnetism, Vol. 31(6), 1995.	
		Iechika, et al., "Performance of hard DLC protective film prepared by PECVD method for thin film magnetic disk," IEEE Transactions on Magnetism, Vol. 30(6), 1994, pp.4134-4136	

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		McKenzie & Veerasamy, "Hydrogen-free amorphous carbon preparation & properties", Diamond Rel. Mat. 3, 1994.	
		Veerasamy, Vijayen S., "Tetrahedral Amorphous Carbon Deposition, Characterisation and Electronic Properties", Dissertation, Univ. of Cambridge, July 1994.	

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